

Title (en)  
METHOD FOR FUNCTIONALISING FLUID LINES CONTAINED IN A MICROMECHANICAL DEVICE, MICROMECHANICAL DEVICE INCLUDING FUNCTIONALISED LINES, AND METHOD FOR MANUFACTURING SAME

Title (de)  
VERFAHREN ZUR FUNKTIONALISIERUNG VON FLÜSSIGKEITSLEITUNGEN EINER MIKROMECHANISCHEN VORRICHTUNG, MIKROMECHANISCHE VORRICHTUNG MIT FUNKTIONALISIERTEN LEITUNGEN UND HERSTELLUNGSVERFAHREN DAFÜR

Title (fr)  
PROCEDE DE FONCTIONNALISATION DES VEINES FLUIDIQUES CONTENUES DANS UN DISPOSITIF MICROMECHANIQUE, DISPOSITIF MICROMECHANIQUE COMPRENANT DES VEINES FONCTIONNALISEES ET SON PROCEDE DE REALISATION

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Application  
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Abstract (en)  
[origin: WO2012001642A1] The present invention relates to a method for functionalising fluid lines (1b) in a micromechanical device, the walls of which include an opaque layer. For this purpose, the invention provides a method for functionalising a micromechanical device provided with a fluid line including a peripheral wall (5) having a surface (2) outside the line and an inner surface (3) defining a space (1b) in which a fluid can circulate, the peripheral wall at least partially including a silicon layer (5a). The method includes the following steps: a) providing a device, the peripheral wall (5) of which at least partially includes a silicon layer (5a) having, at least locally, a thickness (e) of more than 100 nm and less than 200 nm, advantageously of 160 to 180 nm; c) silanising at least the inner surface of the fluid line; d) the localised, selective photo-deprotection on at least the inner surface of the silanised device by exposing the peripheral wall (5) at the point at which said wall has a thickness (e) of more than 100 nm and less than 200 nm, advantageously of 160 to 180 nm.

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**B81C 1/00** (2006.01)

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